



#6A/BM
5902
PATENT
83373.0002

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re application of:

Franklin W. Dabby, et al.

Serial No: 09/894,447

Filed: June 28, 2001

For: PARTICLE DEPOSITION SYSTEM
AND METHOD

Art Unit: 1762

Examiner: Not Assigned

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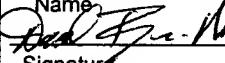
Commissioner for Patents
Washington D.C. 20231, on

April 22, 2002

Date of Deposit

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PRELIMINARY AMENDMENT

BOX NON-FEE AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

Before examining the above-referenced application, please enter the following
amendments:

IN THE CLAIMS:

Please cancel claims 9-10, 12-21, 23-26, and 36-43 without prejudice.

Please replace the text of claim 7 with the following text:

7. (Amended) A deposition system for depositing silica particles onto a
workpiece comprising:

(a) a deposition chamber comprising a plurality of components for
depositing the particles on the workpiece, an inner skin for substantially enclosing
the plurality of components and the workpiece, and an outer skin at least partially

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